

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Chang, *et al.*

Attorney Docket: TSM02-0658

Filed: Herewith

Examiner: TBD

Serial No.: TBD

Art Unit: TBD

For: Holographic Reticle and Patterning Method

Mail Stop: Patent Application  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

The Applicants wish to bring to the attention of the Patent and Trademark Office the information noted on the enclosed form SB-08A that may be considered material to the examination of the above-identified application.

No fee is due at this time, as this Information Disclosure Statement is being filed concurrently with the patent application.

Respectfully submitted,



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March 3, 2004

Date

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<b>Substitute for form 1449A/PTO</b>  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(use as many sheets as necessary)</i>				<b>Complete if Known</b>	
				Application Number	TBD
				Filing Date	Herewith
				First Named Inventor	Chang, <i>et al.</i>
				Art Unit	TBD
				Examiner Name	TBD
Sheet	1	of	1	Attorney Docket Number	TSM02-0658

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code <sup>2</sup> (if known)			
	A	US-3,677,634	07-18-1972	Mathisen	
	B	US-3,712,813	01-23-1973	Ross, <i>et al.</i>	
	C	US-4,734,345	03-29-1988	Nomura, <i>et al.</i>	
	D	US-4,857,425	08-15-1989	Phillips	
	E	US-4,966,428	10-30-1990	Phillips	
	F	US-5,187,372	02-16-1993	Clube	
	G	US-5,504,596	04-02-1996	Goto, <i>et al.</i>	
	H	US-5,528,390	06-18-1996	Goto, <i>et al.</i>	
	I	US-5,774,240	06-30-1998	Goto, <i>et al.</i>	
		US-			
		US-			
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FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> - Number <sup>4</sup> - Kind Code <sup>5</sup> (if known)				
	J	DT-1 331 076	09-19-1973	SIEMENS		

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	K	WOLF, STANLEY, Ph.D. and TAUBER, RICHARD N., Ph.D.; Silicon Processing for the VLSI Era, 2000; pp. 615-635; Volume 1: Process Technology Second Edition; Lattice Press, Sunset Beach, California.	
	L	MÜTZEL, MARIO; "Building 3D Nanostructures with Holograms"; STP-Gateway; April 3, 2002; <a href="http://www.stp-gateway.de/Archiv/archiv475-e.html">http://www.stp-gateway.de/Archiv/archiv475-e.html</a>	
	M	MARDER, SETH, <i>et al.</i> ; "Materials Absorb Two Photons, Generate Acid on Cue"; UniSci Daily University Science News; May 13, 2002; <a href="http://unisci.com/stories/20022/0513023.htm">http://unisci.com/stories/20022/0513023.htm</a>	
	N	STILES, LORI; "Cornell Researchers Collaborate on a Major Advance in Microfabrication"; Cornell Chronicle; May 16, 2002; <a href="http://www.news.cornell.edu/Chronicle/02/5.16.02/Ober-3D_fab.html">http://www.news.cornell.edu/Chronicle/02/5.16.02/Ober-3D_fab.html</a>	

Examiner Signature	Date Considered
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